

Next editions:

- **x** 18th 02.05.2017
- × 19th 08.05.2018

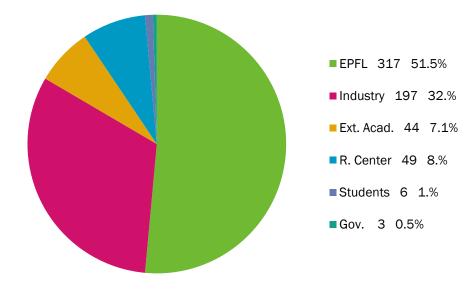
EPFL MICRONANOFABRICATION ANNUAL REVIEW MEETING



WELCOME & THANKS

- ★ Welcome to the 17th edition of the CMi MicroNanoFabrication Annual Review Meeting
- ★ 600 participants registered (with 30% from industry)
- Many thanks for your participation

- Global companies
- Local industry
- Startups
- Suppliers
- Government Agencies
- Researchers
- Faculty members
- Colleagues from other cleanrooms
- -> Traveling from over 12 countries



-> Networking



WELCOME ADDRESS

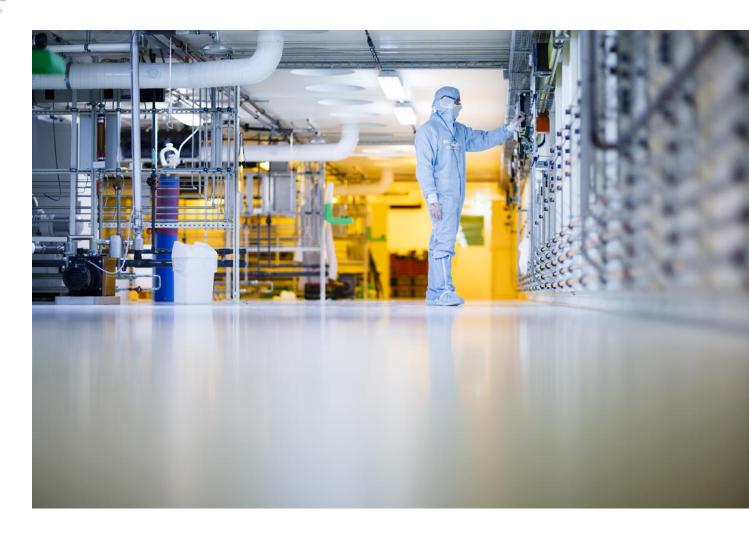
- * Adrienne Corboud Fumagalli
- × Vice-President for Innovation and Technology Transfer





OUTLINE

- V Users
- Staff
- Cleanroom
- × Tools
- Projects







USERS IN 2015

EPFL Engin	eering Sc.	Basic Sc.	Life Sc.	Ext. Ac.	Companies
STI-CMi	STI-IMT-LO	SB-IPHYS-LASPE	SV-BMI-LMNN	EXT-CERN	EXT-Aleva
STI-IBI-BIOS	STI-IMT-LOB	SB-IPHYS-LPMC	SV-GHI-UPKIN	EXT-CSEM	EXT-Asulab
STI-IBI-CLSE	STI-IMT-LPM	SB-IPHYS-LPMV	SV-IBI-LDCS	EXT-EMPA	EXT-Bruker
STI-IBI-LBEN	STI-IMT-LPMAT	SB-IPHYS-LPN	SV-IBI-LLCB	EXT-UNIBS	EXT-Debiotech
STI-IBI-LBNC	STI-IMT-LSBI	SB-IPHYS-LPQM	SV-IBI-UPDEPLA	EXT-UNIBE	EXT-EXALOS
STI-IBI-LBNI	STI-IMT-NAM	SB-IPHYS-LUMES	SV-IBI-UPLUT	EXT-UNIFR	EXT-Hamamatsu
STI-IBI-LHTC	STI-IMT-ESPLAB	SB-ISIC-LEPA	SV-ISREC-CDTSO	EXT-UNIGE	EXT-Hightec
STI-IBI-LNE	STI-IMT-INSTANT-L	SB-ISIC-LIP	SV-ISREC-UPSIM	EXT-UNIL	EXT-Intel
STI-IBI-TNE	STI-IMT-LAI	SB-ISIC-LPI		EXT-WyssCenter	EXT-Karmic
STI-IEL-GR-SCI	STI-IMT-LMTS	SB-ISIC-LSCI			EXT-LémanMicro
STI-IEL-LANES	STI-IMT-OPT	SB-ISIC-LSPM			EXT-LSPR
STI-IEL-LEMA	STI-IMT-PV-LAB		IC-ISIM-LSI		EXT-Lunaphore
STI-IEL-LSM	STI-IMT-SAMLAB		IC-ISIM-LSP		EXT-Mackinac
STI-IEL-NANOLAB	STI-IMX-FIMAP				EXT-Meister-Abrasive
STI-IEL-PHOSL	STI-IMX-LC				EXT-Morphotonix
STI-IEL-POWERLAB	STI-IMX-LMGN				EXT-Nanoworld
STI-IGM-LRESE	STI-IMX-LMM				EXT-Novagan
STI-IMT-GR-LVT	STI-IMX-LMOM				EXT-Patek
STI-IMT-GR-QUA	STI-IMX-LMSC				EXT-Qwane
STI-IMT-LAPD	STI-IMX-LP				EXT-Rolex
STI-IMT-LMIS1	STI-IMX-LTP				EXT-Sigatec
STI-IMT-LMIS2	STI-IMX-SMAL				EXT-SilMach
STI-IMT-LMIS4	STI-IMX-SUNMIL				EXT-Tronics
					EXT-ValFleurier
309 (46)		60 (11)	41 (10)	29 (9)	41 (24)

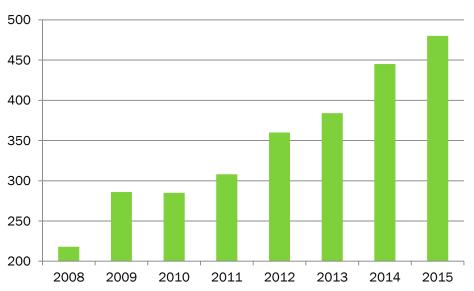


Total: 480 users (+8%) operating the CMi tools

Total: 100 labs (+4%) or companies

USERS IN 2015





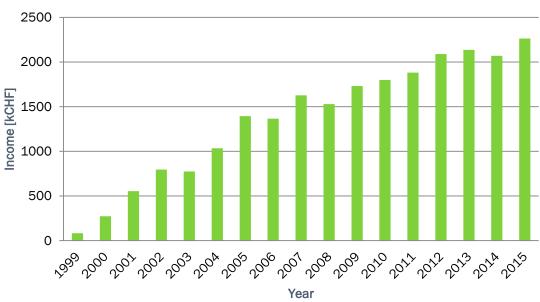
Nanofabrication plays an increasing role in modern science.

- * The number of Users increased over the past 7 years at an average rate of 12% per year
- We have more than doubled the number of Users in 7 years
- Our prevision is to maintain the growth rate around 10% per year for the next 5 years (new labs)
- ★ We will reach the number of 500 Users in 2016
- * We observe some occupancy peaks with more than 50 Users simultaneously in the cleanroom



USERS IN 2015

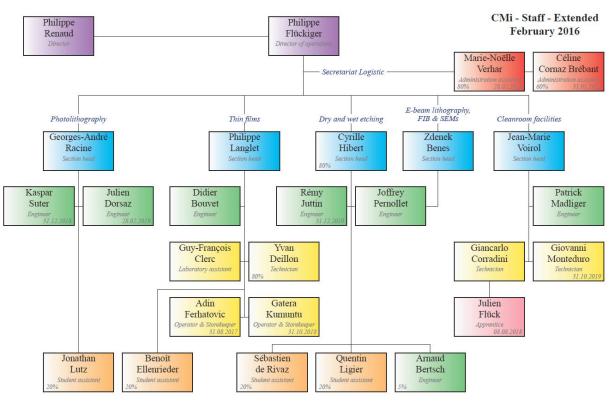




- The fees paid by the users show a regular progression
 - Monthly cap per user is applied
 - Master students operate almost free of charge
- Discussions about the invoicing rules
 - + Eligibility rules from SNSF & Horizon 2020



THE STAFF



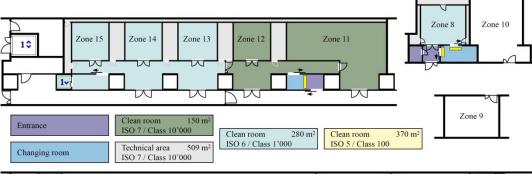
- 19 FTE staff members
- + Student assistants
- * + Apprentices



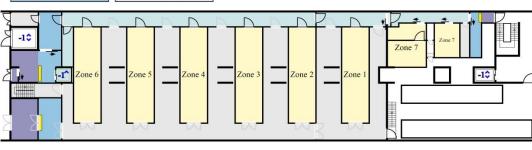
CLEANROOM

CMi BM+1





× CMi BM-1



Initial surface (1998)	Extension (2010)	Total surface
1000m ²	300m ²	1300m ²

- ★ We have a total cleanroom surface of 1300m² on two levels connected by an elevator
- The cleanroom is almost full
- New space is required for installing new tools



TOOLS INSTALLED/PURCHASED IN 2015

- **x** Electronics Upgrade of the 10 existing furnaces
- Installation of a TEOS furnace



- Coater Developer
 - + SUSS ACS200 Gen 3



- Mask Aligner
 - + SUSS MA6 Gen3



SUCCESSFUL R'EQUIP 2015

- ALD tool for coating high aspect ratio materials
 - + Prof. Jeremy Luterbacher
 - + Coating of particles [& magnetic materials (Ni₈₀Fe₂₀)]
 - + Deadline for public tender: 02.05.2016



- RIE for etching dielectrics with ultra low roughness
 - + Prof. Tobias Kippenberg
 - Etching of Dielectrics with ultra low roughness
 - + Deadline for public tender: 02.05.2016



WHISH LIST FOR THE FUTURE?

Maskless Aligner?

- + Direct exposure of photoresist
- + In beta-site in CMi



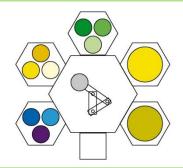
New EBEAM writer?

- + Better performances
- + Speed, Image placement, Field size, Edge fracturing
- + Stability & Uniformity



PVD Cluster Tool ?

- + Thin film deposition of dielectric materials
- + Multilayers & Bragg reflectors
- + Co-sputtering of metals, nitrides & oxides





REQUESTS DIRECTLY FROM LABS?

Plasma enhanced Chemical Vapor Deposition system
--

Pulsed Laser Deposition system ?

- × Vapor HF etcher?
 - + For the release of MEMS without stiction



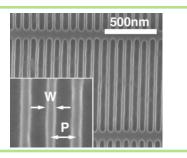
PUBLICATIONS HIGHLIGHTS 2016

Over the last 12 months, 6 papers were published in Nature & Science with devices produced in CMi.

1° Science 10 Jul 2015: Vol. 349, Issue 6244, pp. 165-168 DOI: 10.1126/science.aab2051

Mid-infrared plasmonic biosensing with graphene

Plasmonic graphene biosensors

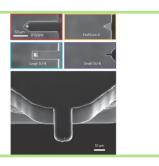


4

Nature Nanotechnology 23 Nov 2015 Volume: 11, Pages:147-151 doi:10.1038/nnano.2015.254

Harnessing the damping properties of materials for high-speed atomic force microscopy

AFM tips

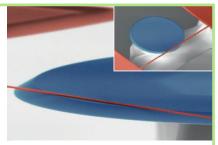


2°

Nature 10 August 2015 Vol. 524, pp. 325–329 doi:10.1038/nature14672

Measurement-based control of a mechanical oscillator at its thermal decoherence rate

Mechanical oscillators



5°

Science 22 Jan 2016: Vol. 351, Issue 6271, pp. 357-360 DOI: 10.1126/science.aad4811

Photonic chip-based optical frequency comb using soliton Cherenkov radiation

Photonic chips

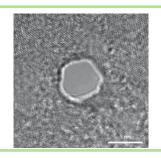


3°

Nature Nanotechnology 21 September 2015 Volume: 10, Pages:1070–1076 doi:10.1038/nnano.2015.219

Identification of single nucleotides in MoS2 nanopores

MoS2 nanopores biochips

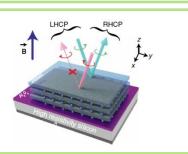


6°

Nature Communications 6 Apr 2016 Volume: 7, Article number: 11216 doi:10.1038/ncomms11216

Near optimal graphene terahertz non-reciprocal isolator

Teraherz graphene devices







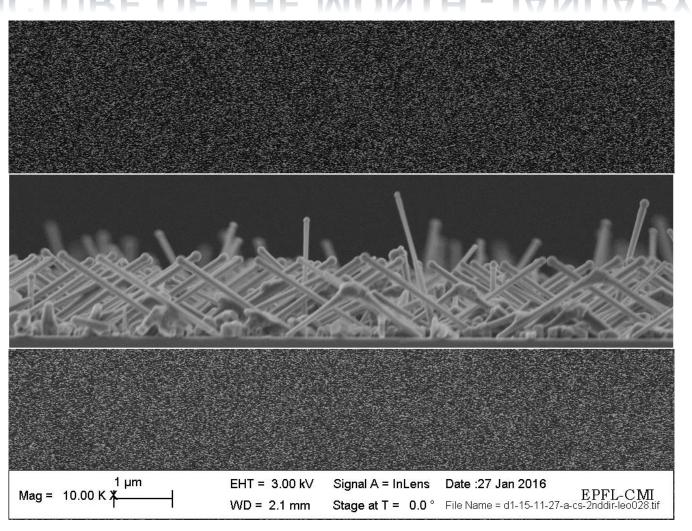
ERC GRANTS 2016



- × 7 professors using the CMi have received an ERC Grants this year ©
- 2 advanced + 2 consolidators + 2 starting + 1 Proof of concept



PICTURE OF THE MONTH - JANUARY

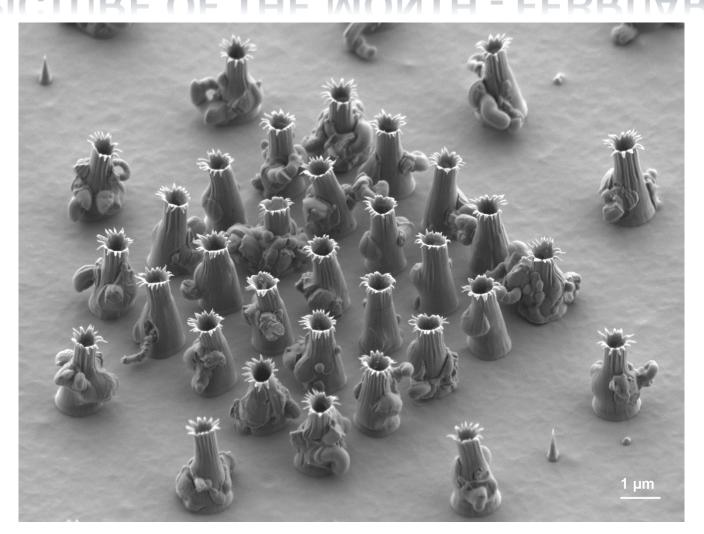


Micro-matchstick carpet Mahdi Zamani, LMSC





PICTURE OF THE MONTH - FEBRUARY

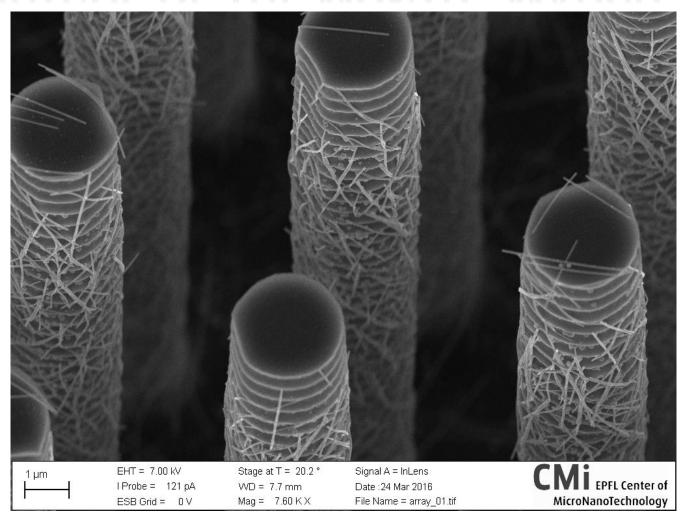


Sunflower party Benoît Desbiolles, LMIS4 Valentin Flauraud, LMIS1





PICTURE OF THE MONTH - MARCH



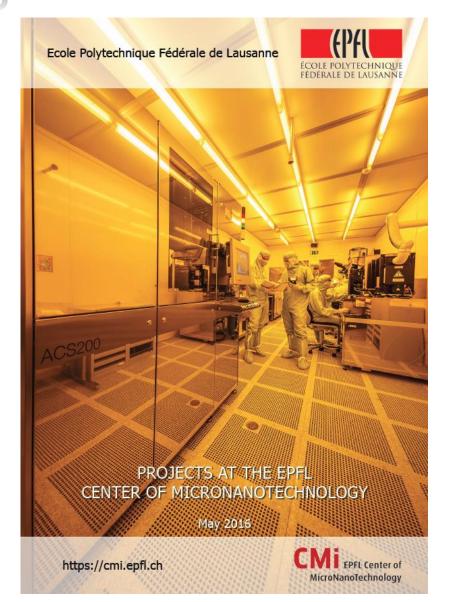
Liana around antic columns Dmitry Mikulik, LMSC Jelena Vukajlovic, LMSC





ABSTRACTS IN 2016

217 posters collected in the brochure





PROGRAM

- Very exciting program
- x 10 presentations
- Spanning an exceptionally broad range
- **x** Try to be different every year different
- Not always invite the heavy users
- Emphasize on the new Professors @ EPFL
- Sometime also some exotic users
- One common point:
 - MicroNanoFabrication





MicroNanoFabrication Annual Review Meeting

Date: Tuesday May 3rd, 2016 Time: 09h30 – 17h00 Place: EPFL, Forum Rolex Learning Center, RLC E1 240

Program:

09h30-10h00	Coffees and Croissants, Distribution of Badges and Proceedings
10h00-10h05	Adrienne Corboud Fumagalli, Vice President for Innovation and Technology Transfer, Welcome address
10h05-10h15	Philippe Flückiger (http://cmi.epfl.ch), Introduction
10h15-10h45	Takao Someya, Organic Transistor Lab, The University of Tokyo, Microfabrication and flexible organic devices for wearable electronics
10h45-11h00	Giovanni de Micheli (http://lsi.epfl.ch), SiNW controllable-polarity transistors
11h00-11h15	Niels Quack (http://q-lab.epfl.ch), Scalable on-chip optical switches based on silicon photonic MEMS
11h15-11h45	Break
11h45-12h00	Aleksandra Radenovic (http://lben.epfl.ch), Nature inspired engineering-2D nanopores
12h00-12h15	Dirk Grundler (http://lmgn.epfl.ch), Nanomagnets for magnonics: shrinking microwaves to the nanoscale
12h15-12h30	Diego Ghezzi (http://lne.epfl.ch), Neuroprosthetics for vision restoration
12h30-14h30	Lunch & Poster Session
14h30-14h45	Raphaël Butté (http://laspe.epfl.ch), Short-wavelength III-nitride nanophotonic structures: a novel testbed for nanofabrication
14h45-15h00	Eyad Assaf (http://hightec.ch), HiCoFlex Technology, new dimensions of flexible multilayer HDI
15h00-15h30	Break
15h30-15h45	Nikos Stergiopulos (http://lhtc.epfl.ch), Using CMi capacities for the fabrication of implantable devices
15h45-16h00	Sébastien Lani (http://csem.ch), Light steering with a MEMS scanner
16h00-17h00	Cocktails & Poster Session





ENJOY THE CONFERENCE





THANKS FOR YOUR ATTENTION



